

METHOD AND PROCESSING SYSTEM FOR DETERMINING COATING
STATUS OF A CERAMIC SUBSTRATE HEATER

ABSTRACT OF THE DISCLOSURE

A method and system for monitoring coating status of a ceramic substrate heater in a process chamber. The method includes heating a ceramic substrate heater to a desired temperature, exposing the ceramic substrate heater to a reactant gas during a process, and monitoring optical emission from the heated ceramic substrate heater to determine coating status of the ceramic substrate heater. Processes that can be monitored include a chamber cleaning process and a chamber conditioning process.